## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hiroki Nakamura et al.

Serial No.: 10/586,400 Filed: April 20, 2007

For: VACUUM DEPOSITION METHOD AND SEALED-TYPE

EVAPORATION SOURCE APPARATUS FOR VACUUM DEPOSITION

Art Unit: 1715

Examiner: Gambetta, Kelly M. Att'y. Docket: 520514.00039

Confirmation No: 3841

## **Response to Restriction Requirement**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to a restriction requirement in the Office Communication mailed on April 26, 2010 for the above application, Applicant elects claims 9-16 of Group 2 drawn to an evaporation source apparatus. Applicant reserves the right to file divisional applications containing the unelected claims.

No additional fees for filing this response are believed to be due. However, if such fees are due, the Commissioner is hereby authorized to charge them to deposit account no. 17-0055.

Respectfully submitted,

Daniel G. Radler Reg. No. 43,028

Quarles & Brady LLP

411 East Wisconsin Avenue Milwaukee, Wisconsin 53202

Tel. No. (414) 277-5000